

DEVICE FOR CONFINING SURFACE PHONON-POLARITONS AND METHOD FOR FORMING THE SAME

ABSTRACT

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According to embodiments of the present invention, a device for confining surface phonon-polaritons is provided. The device includes a polar crystal substrate configured to support the surface phonon-polaritons in the device, and a layer having elemental germanium, the layer being arranged on the polar crystal substrate to confine the surface phonon-polaritons, wherein
10 the layer has a thickness of about 50 nm or less. According to further embodiments of the present invention, a method for forming a device for confining surface phonon-polaritons is also provided.

Figure 2A